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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Christine Hau-Riege : Group Art Unit: 2823

Application No.: 10/697,214 : Examiner: William M. Brewster

Filed: October 29, 2003 :

Title: SEMICONDUCTOR COMPONENT AND METHOD FOR PRECLUDING STRESS-INDUCED VOID FORMATION IN THE SEMICONDUCTOR COMPONENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT TRANSMITTAL

1. Transmitted herewith is a Amendment for this application.
2. The fee for claims has been calculated as follows:

CLAIMS AS AMENDED						
	Claims After <u>Amendment</u>	No. Prev. <u>Paid For</u>	Present <u>Extra</u>	Rate - Small	Add'l <u>Fee</u>	
Total	18	-	22 = 0	\$50.00	=	0.00
Indep.	3	-	3 = 0	\$200.00	=	0.00
Filing Fee Calculation:						<u>\$0.00</u>

3. The total fees to be paid are as follows and are enclosed payable to the Commissioner of Patents and Trademarks:

Fee for claims adjustment:	0.00
Extension fee:	<u>0.00</u>
Total Fees Due:	<u>\$0.00</u>

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Amendment Transmittal

4. Applicant believes there are no additional fees required for these filings. The Commissioner is hereby authorized to charge any deficiency to Deposit Account No. 50-2173.

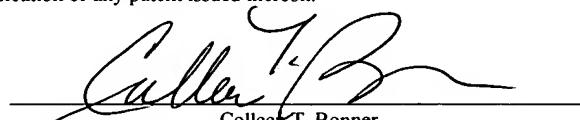
Respectfully submitted,

Dated: 19 January 2005 By Rennie William Dover
Rennie W. Dover, Reg. No. 36,503
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Telephone: (602) 322-4000

CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8

I hereby certify that this document (and any as referred to as being attached or enclosed) is being deposited with sufficient postage as first class mail with the United States Postal Service on January 19, 2005 and addressed to Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

I hereby declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code, and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.



Colleen T. Bonner

CAVPHXDB:1142947.1

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AMENDMENT

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Madam/Sir:

In response to the Office action mailed December 15, 2004, please amend the application as follows: